JEOL JSM-IT800SHL Scanning Electron Microscope (SEM)

The JEOL JSM-IT800SHL is a high-resolution field emission SEM equipped with in-lens detectors (UED and UHD), a secondary electron (SE) detector, and a back-scattered electron (BSE) detector for comprehensive imaging capabilities. It offers various observation modes, including beam deceleration and a Super Hybrid Lens system, enabling high-contrast imaging across a wide range of materials.

The system is also equipped with an Oxford 170 mm^2 EDS detector for rapid, high-sensitivity elemental analysis, a Raith electron beam lithography (EBL) module for precise nanofabrication, a plasma cleaner for sample cleaning and chamber maintenance, and an anaerobic transfer system for handling air-sensitive samples.